



648.43545X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: M. YAKUSHIJI, et al.
Serial No: 10/787,461
Filed: FEBRUARY 27, 2004
Title: PLASMA ETCHING APPARATUS AND PLASMA ETCHING METHOD
Group AU: 1763
Examiner: Luz L. Alejandro Mulero
Confirm. No: 7834

AMENDMENT

Mail Stop: AMEND - FEE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

March 30, 2006

Sir:

In response to the Office Action mailed November 30, 2005, the period for response having been extended for one (1) month by the attached Petition for Extension of Time, please amend the above-identified application as listed in the following, and as set forth on the following pages:

AMENDMENTS TO THE CLAIMS; and

REMARKS are included following the amendments.